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Ultrafast relativistic-energy electron microscopy

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Motivations



(1) Commercial Electron Microscopy

- A powerful tool to observe the static image of atomic structures in materials
- Spatial resolution: <0.1 nm

Ex.: Images of Au atoms in vacuum observed by 300-keV TEM



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Motivations



(2) Ultrafast Electron Microscopy(UEM)

• UEM can observe a structural movie for study of dynamics in materials.



 However, the temporal resolution of single-shot measurement is

~10 ns

which is limited by the electron pulse length under the low-energy region.

UEM and its applications

Methods



Imaging Technology

Structural observation and imaging in "real space" with atomic-scale spatial resolution using high-energy electron beam.

nm



Imaging in "real space"

Pump laser pulse

Ultrafast Observation



Observations of fundamental dynamic processes in matter occurring on femtosecond time scales over atomic spatial dimensions.

Observation in "real time"

UEM and its applications

Methods



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Imaging in "real space"

Protein Structural Dynamics



Protein structural dynamics
Macromolecular structure
Reveal of functioning processes

•New technologies and applications in medical biology.

Targets

Making Molecular Movie



•Observation of single molecule motion.

•Ultrafast chemical reactions •Solvation dynamics •Discovery of transition states

•Discovery of transition states and reaction intermediates.

Pump laser pulse



Ultrafast Observation



Observations of fundamental dynamic processes in matter occurring on femtosecond time scales over atomic spatial dimensions.

Observation in "real time"

Nano-technology/science

•Dynamics of phase transients in solidstate materials.

•Creation of new functional materials and devices for nanotechnology.



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✓ Space-charge induced force can be reduced.

$$\vec{F}^{sc} \cong e\vec{E}^{sc} / \gamma^2$$

Beam energy using RF gun: 3 MeV 4

In our experiment, 100-fs electron pulses at 3 MeV and 1~10 pC are possible.

The space-charge induced force can be reduced by 10⁻³ comparing with 100 KV TEM.

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✓ Femtosecond single-shot imaging is realizable.

- Possibility for study the irreversible phenomena or reactions
- Observation before damage for biomolecules

What is RF gun?



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The expected beam parameters:

Electron energy:	1~3 MeV
Bunch length:	100 fs
Norm. emittance:	0.1 mm-mrad
Energy spread:	10 ⁻⁴ (10 ⁻⁵ for challenge)
No. of electrons:	10 ⁷ ~10 ⁸ e-'s/pulse

essential parameters for EM!

100 fs electron pulse generation



Bunch length is dominated by space-charge effect!

100 fs electron pulse generation



can be generated at beam energy of ≥ 2 MeV.

0.1µm- emittance & fs-bunch electron beam

(1) <u>reduce the thermal emittance</u> by focusing laser on the cathode



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(2) <u>collimate emittance after RF gun</u>



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(1) <u>reduce the thermal emittance</u> <u>by focusing laser on the cathode</u>



RF electron gun based Ultrafast Electron Microscopy (UEM) (The first prototype in world)

Concept of RF gun based UEM



Femtosecond photocathode electron gun



1~3 MeV
100 fs
0.1 mm-mrad
10 ⁻⁴ (10 ⁻⁵ for challenge
10 ⁷ ~10 ⁸ e-'s/pulse

Time resolution:100 fsSpatial resolution:10 nm





Size: 3m(H) x 0.7m(D)

mirror (5µm)

X, e

ORCA-R² CCD

MeV ED imaging using fs e- pulses

Electron diffraction imaging in UEM

Sample: Single-crystal Au Thickness: ~10nm

Electron beam: Energy: 3.1 MeV Pulse length: 100 fs e- charge: ~1pC/pulse

Results:

High-quality electron diffraction patterns can be observed with MeVenergy single e- pulse.

Ultrafast dynamics: Laser induced melting in Au

MeV EM imaging using fs e- pulse

Electron beam: 3.1 MeV, 100 fs, ~1pC/pulse

Sample: Au nanoparticles (diameter: 400nm)

First demonstration of EM imaging using MeV femtosecond electron beam!

MeV EM imaging using fs e- pulse

Electron beam: 3.1 MeV, 100 fs, ~1pC/pulse

Sample: polystyrene latex particles (diameter: 1.09µm)

Single-shot and accumulated imaging

Dependence on No. of electron pulses

<u>e- beam</u>: 3.1 MeV, 100 fs, ~1pC/pulse

<u>Sample</u>: Au nano-particles (diameter: ~400nm)

➤Under the low-magnification observation,

the single-shot imaging using a femtosecond electron pulse is available in future.

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Conclusions

- RF gun based ultrafast electron microscopy (UEM) have been constructed at Osaka University.
 - In UED exp., single-shot and time-resolved measurements have been succeeded. The time resolution was achieved to be ~100 fs.
 - In UEM exp., the demonstrations of MeV electron imaging were carried out.
- Both experiments suggest that RF gun is very useful for ultrafast electron diffraction and is also expected to be used in ultrafast electron microscopy.

However, great efforts and many challenges are required:

≻ reduce further the emittance (<0.1 μ m) and energy spread (10⁻⁵ or less),

➢increase the beam brightness overcoming space-charge effect,

➢improve the stabilities on the charge and energy,

➤improve the spatial resolution, ...

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